

# Micro Ilon RIE

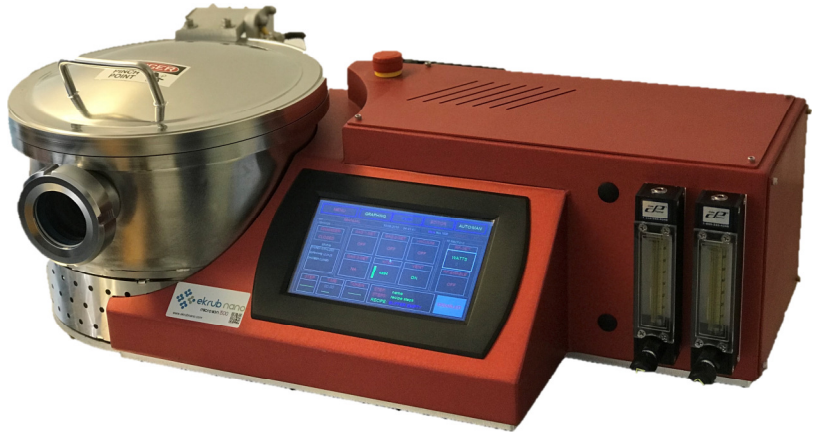
## Features and Benefits

The **micro Ilon** is built around an anodized aluminum cabinet with a side-mounted reaction stainless steel chamber.

All other components are mounted within this cabinet with the exception of the vacuum pump which is located externally.

### Process Chamber/Substrate Assembly

The Micro Ilon RIE process chamber is capable of processing one 150mm or custom IC packages. The platen can be either heated or cooled through a temperature controlled water liquid source.



### Touch Screen Control Module

Process gases, and RF power set point, are set, and monitored, and controlled by the integrated touch screen control panel GUI. All gases and RF power can be independently controlled during Manual, or recipe process control..

### 1.3.5 Gas Inlet Control System

The Micro Ilon RIE system standard configuration has two channels Rotameter flow meters, optionally up to a total of three channels can be ordered. All gas channels are isolated with stainless steel process isolation gas valves.

### 1.3.6 RF Generator Sources

The system includes a 300 watt 30 kHz power supply for plasma

## Applications

- FAILURE ANALYSIS, DE-ENCAPSULATION
- ETCHING OF OXIDES, SILICON, NITRIDES, POLYIMIDES
- Typical process gases O<sub>2</sub>, Ar, He, CF<sub>4</sub>, SF<sub>6</sub> and SF<sub>6</sub>

# Specifications: Micro IIon RIE Plasma System

<b>Enclosure Dimensions</b>	<b>W x D x H – Footprint</b>	W x D x H – Footprint L 673mm D 220.00 mm W 215.00mm
	<b>Net Weight</b>	27.2155 kg 60 pounds
<b>Chamber</b>		6" Powered Working Area 152 mm Diameter (6.0 in. Diameter)
<b>Electrode</b>	<b>Electrode Height</b>	12.7 mm (0.5 in.)
<b>RF Power</b>	<b>Standard Wattage</b>	Standard Wattage 300 watts
	<b>Frequency</b>	30 kHz
<b>Gas Control</b>	<b>Maximum Number of rotameters</b>	3
<b>Control &amp; Interface</b>	<b>Software Control</b>	Windows10, PLC I/O with 7 inch Touch Screen
<b>Vacuum Pump</b>		Standard Pump CFM 20 cfm (not included)
<b>Facilities</b>	<b>Process Gas Fitting Size &amp; Type</b>	6.35 mm (0.25 in.) OD Swagelok Tube
	<b>Process Gas Purity</b>	Lab or Electronic Grade
	<b>Process Gas Pressure</b>	0.69 bar (10 psig) min. to 1.03 bar (15 psig) max.
	<b>Vent Gas</b>	Purge Gas Fitting Size & Type 6.35 mm (0.25 in.) OD Swagelok Tube
	<b>Purity</b>	Lab or Electronic Grade
	<b>Vent Gas Pressure</b>	0.69 bar (10 psig) min. to 1.03 bar (15 psig) max.
<b>Exhaust</b>	<b>Exhaust</b>	KF 25 1.57mm
<b>Facilities Equipment</b>	<b>Facilities</b>	Chiller, Scrubber

For more information contact us at [sales@semistarcorp.com](mailto:sales@semistarcorp.com) or [semistarcorp.com/product/micro-iiion-rie-reactive-ion-etching](http://semistarcorp.com/product/micro-iiion-rie-reactive-ion-etching)